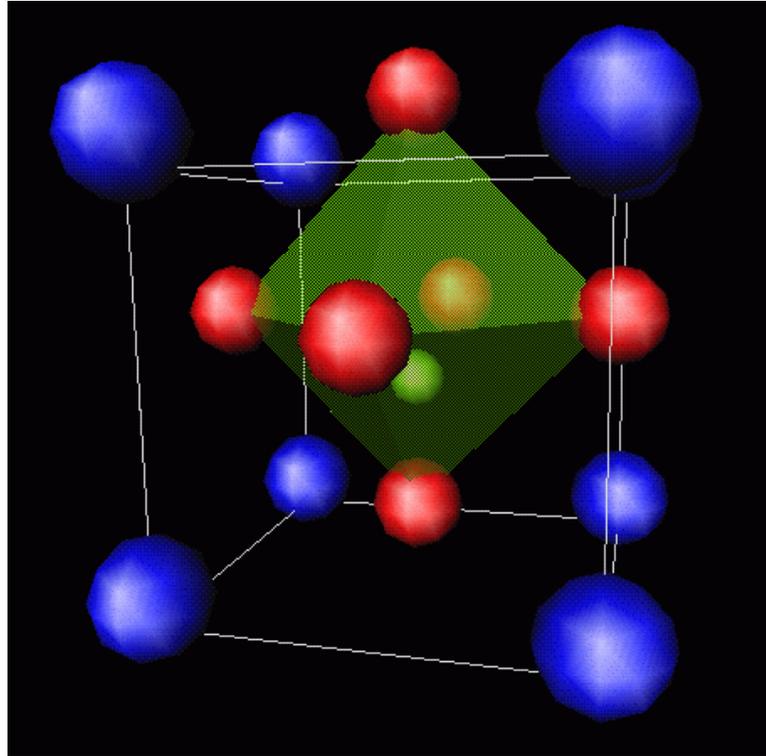


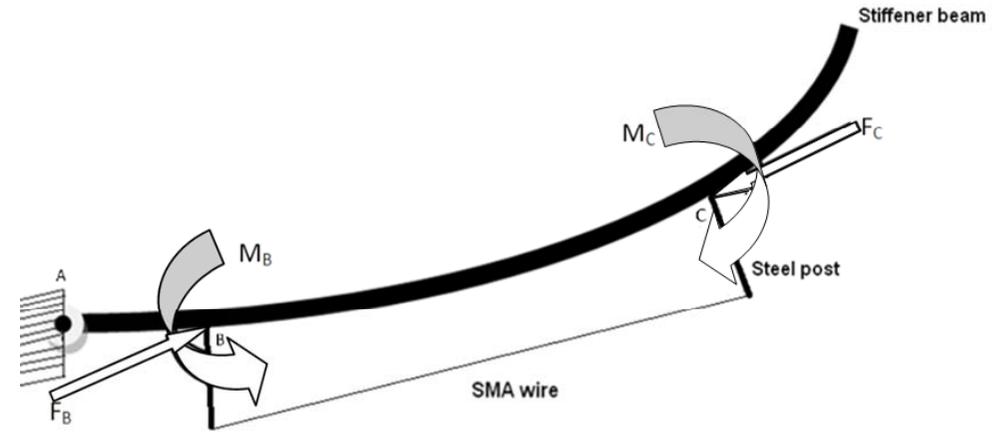
# Modelling of Smart Materials



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## LECTURE 8

# Modelling of Piezoelectric Material (Part 1)

# Organization

- **Piezoelectric Property**
- **Crystal Structure**
- **Constitutive Relationship**
- **Active Strain Evaluation**

<b>Output Input</b>	<b>Current/Charge</b>	<b>Magnetization</b>	<b>Strain</b>	<b>Temperature</b>	<b>Light</b>
<b>Electric Field</b>	<b>Conductivity Permittivity</b>	<b>Electromagnetic Effect</b>	<b>Reverse Piezoelectric Effect</b> SA	<b>Ohmic Resistance</b>	<b>Electro-Optic effect</b>
<b>Magnetic Field</b>	<b>Eddy Current Effect</b>	<b>Permeability</b>	<b>Joule Effect Magnetostriction</b> SA	<b>Magneto-caloric Effect</b>	<b>Magneto-Optic effect</b>
<b>Stress</b>	<b>Direct Piezoelectric Effect</b> SS	<b>Villary Effect</b> SS	<b>Elastic Modulus</b>	<b>Thermo- Mechanical Effect</b> SS	<b>Photo-elastic Effect</b> SS
<b>Heat</b>	<b>Pyroelectric Effect</b>	<b>Thermo- magnetization</b>	<b>Thermal Expansion/Phase Transition</b> SA	<b>Specific Heat</b>	<b>Thermo- luminescence</b>
<b>Light</b>	<b>Photo-voltaic Effect</b>	<b>Photo- magnetization</b>	<b>Photostriction</b> SA	<b>Photo-thermal effect</b>	<b>Refractive Index</b>

Properties important for Actuation	Piezoelectric Material		Magnetostrictive Material	Phase-transition dependent Material	
	Piezo-ceramic	PVDF	Terfenol-D	Nitinol	FSMA
Maximum free strain ( $\Delta$ ) in microns	2000	700	2000	20,000	30,000
Young's Modulus (GPa)	60-70	2-3	48	27.5 M-phase, 90 A-phase	0.45 – 0.82
Bandwidth	0.1 Hz-GHz	0.1 Hz-GHz	0.1 Hz-10KHz	0-10 Hz	100 Hz

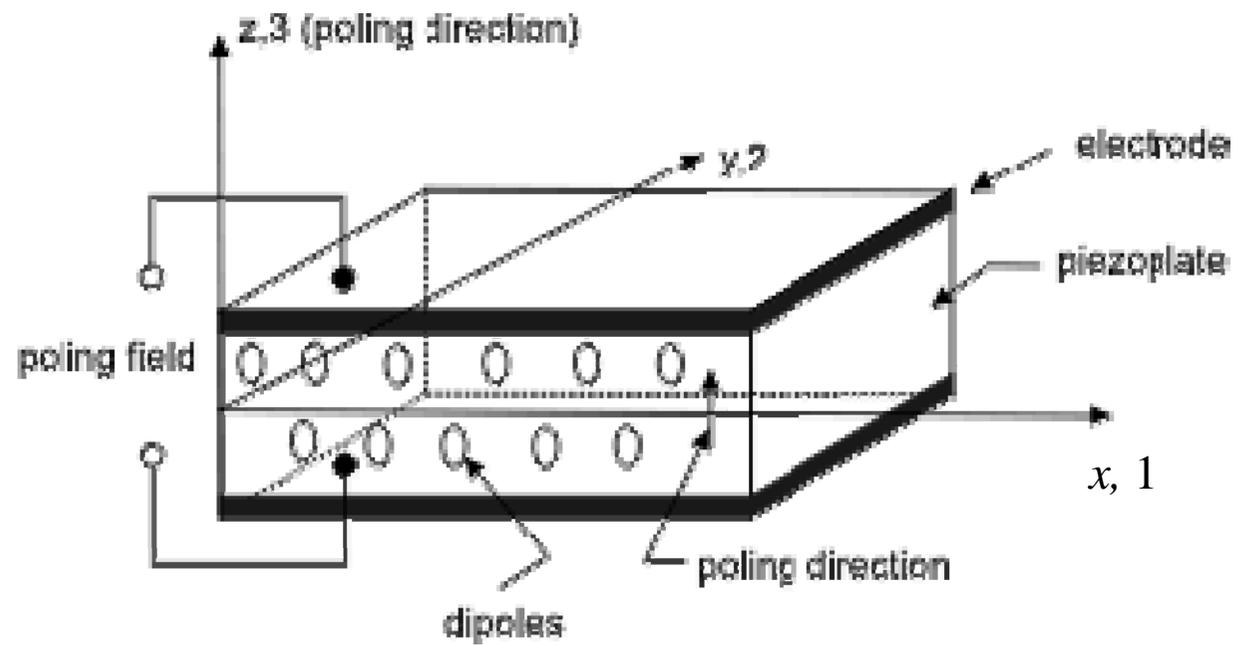
# Fundamental equations of piezoelectricity

$$\sigma_{ij} = C_{ijkl}^E S_{kl} - e_{kij} E_k$$

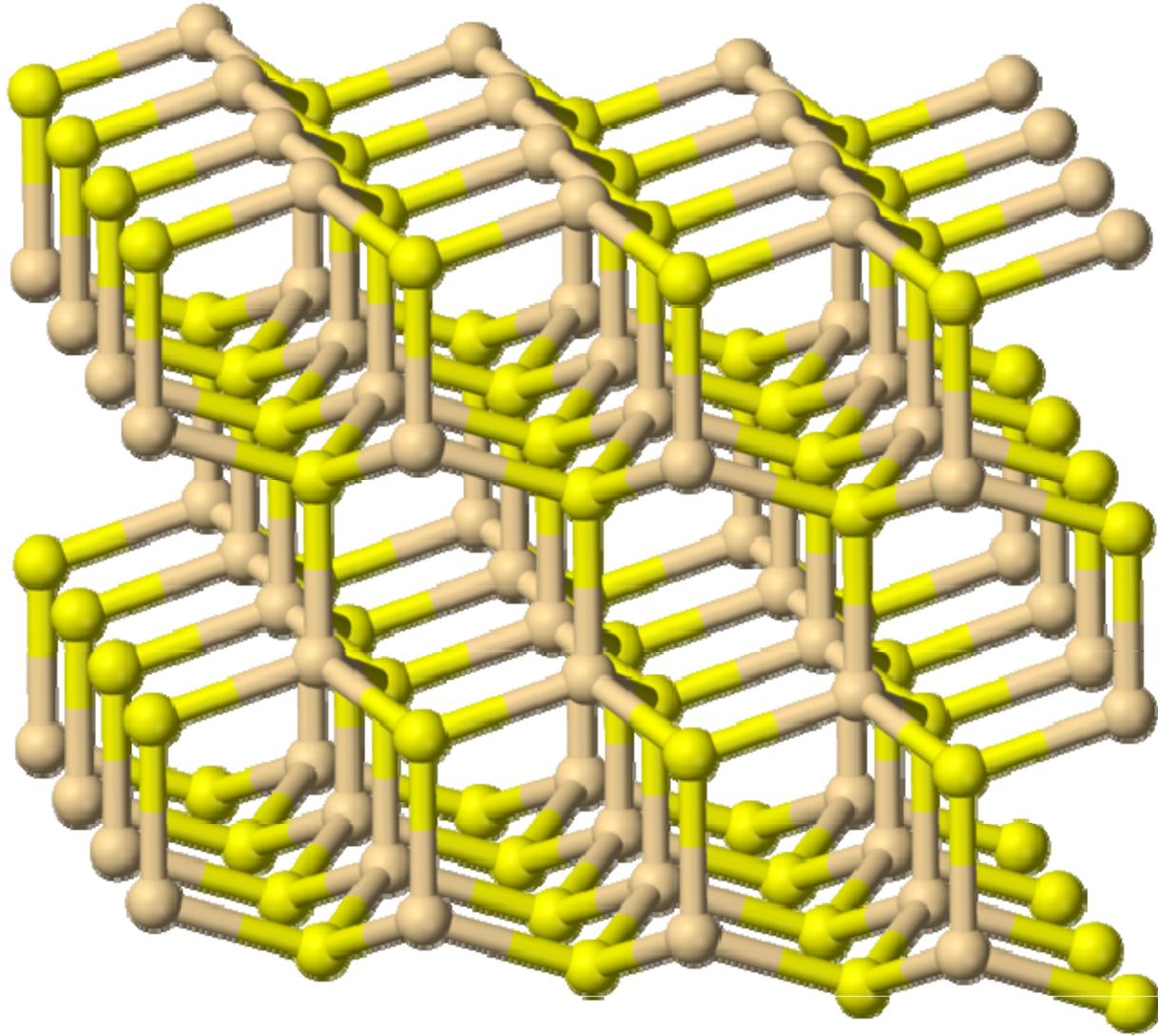
$$D_i = e_{ikl} S_{kl} + \epsilon_{ij}^S E_j$$

where, the subscripts  $i, j, k, l = 1, 2, 3$  denotes tensorial indices. The stress tensor is represented by  $\sigma$ ,  $S$  is the strain tensor,  $E$  is the electric field intensity and  $D$  is the electric displacement field. Elastic stiffness matrix is denoted by the symbol  $C^E$ , where the superscript  $E$  denotes that the elastic constant is measured under constant electric field;  $e$  is the piezoelectric stress-charge matrix and  $\epsilon$  the permittivity matrix, similar to  $C$ , is measured under constant strain-condition.

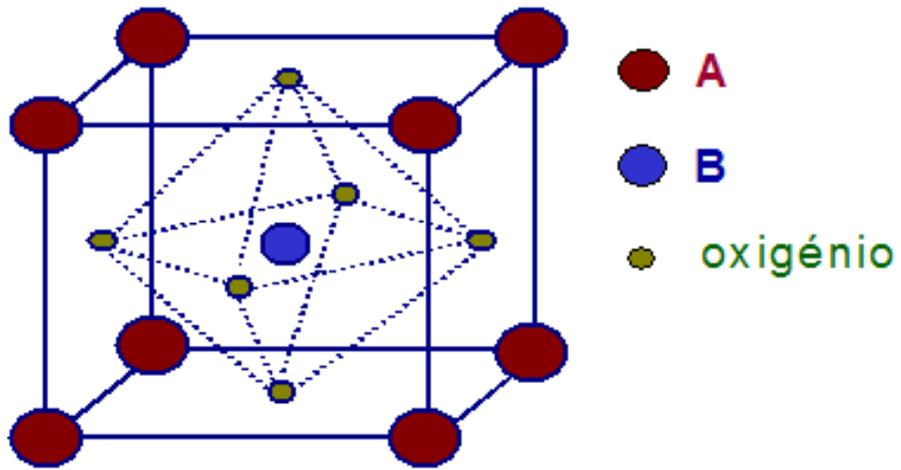
# Different Axes



# Di Hexagonal Crystal Symmetry



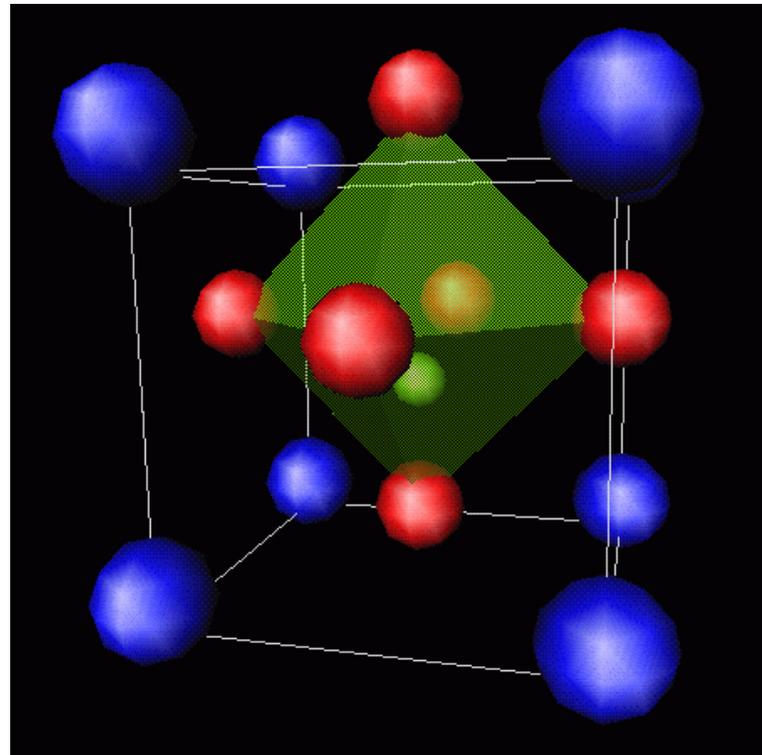
Greenockite Crystal



Perovskite Structure with 4mm crystal symmetry



Tetragonal Wulfenite



# Outcome of Symmetry

The crystal structure of common piezoelectric materials shows 4mm or 6mm symmetry. Following material symmetry conditions could be applied to the constitutive relationship

$$C_{ijkl} = C_{jikl} = C_{klij}$$

$$e_{kij} = e_{kji}$$

$$\varepsilon_{ij} = \varepsilon_{ji}.$$

$$\begin{Bmatrix} \sigma_x \\ \sigma_y \\ \sigma_z \\ \sigma_{yz} \\ \sigma_{xz} \\ \sigma_{xy} \\ D_1 \\ D_2 \\ D_3 \end{Bmatrix} = \begin{bmatrix} C_{11} & C_{12} & C_{13} & 0 & 0 & 0 & 0 & 0 & -e_{31} \\ C_{12} & C_{11} & C_{13} & 0 & 0 & 0 & 0 & 0 & -e_{31} \\ C_{13} & C_{13} & C_{33} & 0 & 0 & 0 & 0 & 0 & -e_{33} \\ 0 & 0 & 0 & C_{44} & 0 & 0 & 0 & -e_{15} & 0 \\ 0 & 0 & 0 & 0 & C_{44} & 0 & -e_{15} & 0 & 0 \\ 0 & 0 & 0 & 0 & 0 & C_{66} & 0 & 0 & 0 \\ 0 & 0 & 0 & 0 & e_{15} & 0 & \varepsilon_1 & 0 & 0 \\ 0 & 0 & 0 & e_{15} & 0 & 0 & 0 & \varepsilon_2 & 0 \\ e_{31} & e_{31} & e_{33} & 0 & 0 & 0 & 0 & 0 & \varepsilon_3 \end{bmatrix} \begin{Bmatrix} S_x \\ S_y \\ S_z \\ S_{yz} \\ S_{xz} \\ S_{xy} \\ E_1 \\ E_2 \\ E_3 \end{Bmatrix}$$

The electro-mechanical coupling is shown inside the bordered boxes . Axes 1, 2 and 3 used for the electrical system are identical with x, y and z, corresponding to the mechanical system.

# Simplified Equation for Piezo-patch

- Ignoring the normal stress  $\sigma_z$  and the shear stresses  $\sigma_{xz}$  and  $\sigma_{yz}$  for plane stress assumption:

$$\begin{Bmatrix} S_x \\ S_y \\ S_{xy} \\ D_3 \end{Bmatrix} = \begin{bmatrix} 1/E_p & -\nu/E_p & 0 & -d_{31} \\ -\nu/E_p & 1/E_p & 0 & -d_{32} \\ 0 & 0 & 2(1+\nu)/E_p & 0 \\ d_{31} & d_{32} & 0 & \epsilon_{33} \end{bmatrix} \begin{Bmatrix} \sigma_x \\ \sigma_y \\ \sigma_{xy} \\ E_3 \end{Bmatrix}$$

$E_p$  is the modulus of elasticity of the piezoelectric material,  $\nu$  is the Poisson's ratio and  $d_{ij}$  are the piezoelectric strain-charge constants

# Active Strain Expression

If a piezoelectric thin slab is subjected to mechanical load, the total strain  $S$  developed in an active layer, would consist of two parts – the structural or elastic strain  $S_s$  and the piezoelectric strain  $S_a$  such that

$$S = S_s + S_a$$

where,  $S_a = [-d_{31}E_3, -d_{32}E_3, 0]^T$ .

To generate strains along the direction of the thickness of the specimen, ceramics with different crystal-cuts are used which are commonly known as Piezo-stacks. The electro elastic coupling components in the 3-3 directions, like  $d_{33}$  or  $e_{33}$ , become important in such cases.

# References

- Gauenzi, P., Smart Structures, Wiley, 2009
- Cady, W. G., Piezoelectricity, Dover Publication, 1950
- Crawley, E. F., Intelligent Structures for Aerospace: a technology overview and assessment, AIAA, 33 (8), 1994, pp. 1689-1699

**END OF LECTURE 8**